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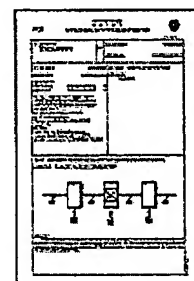
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34 p

**Published / Filed:** **2000-02-24 / 1999-08-05****Application** **WO1999JP0004224**

Number:

**IPC Code:** **B01J 21/06**; **B01D 53/86**;**ECLA Code:** **B01D53/86L**; **B01J21/04**;**Priority Number:** 1999-03-04 **JP1999000056754****Abstract:** A method and apparatus for decomposing a fluorochemical, e.g., C<sub>2</sub>F<sub>6</sub>, by bringing a waste gas (1) containing the fluorochemical into contact with an aluminum oxide (3), e.g., .ggr.-alumina, heated at, e.g., 800 to 900 °C. H<sub>2</sub> may be present therein in an amount sufficient for converting the fluorine atoms of the fluorochemical to HF. The fluorochemical can be decomposed to a high degree. The aluminum oxide has a long life, and CO generation is little. [\[French\]](#) [\[Japanese\]](#)**Attorney, Agent** **SHAMOTO, Ichio** ;  
or Firm:**INPADOC** [Show legal status actions](#)Buy Now: [Family Legal Status Report](#)

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**Designated** **JP KR US, European patent: DE FR GB**

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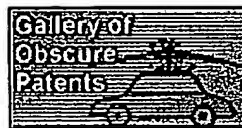
References:

Buy PDF	Patent	Pub.Date	Inventor	Assignee	Title

	<a href="#">US6790421</a>	2004-09-14	Mori; Yoichi	Ebara Corporation	<a href="#">Method for treating exhaust gas containing fluorine-containing compou</a>
	<a href="#">US6764666</a>	2004-07-20	Mori; Yoichi	Ebara Corporation	<a href="#">Process for treating gas containing fluorine-containing compounds and C</a>

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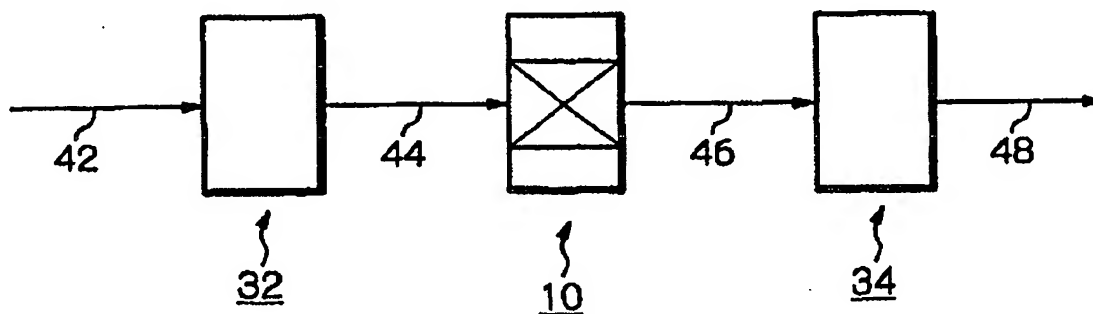
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特許協力条約に基づいて公開された国際出願

<p>(51) 国際特許分類6 B01J 21/06, B01D 53/86</p>	<p>A1</p>	<p>(11) 国際公開番号 WO00/09258</p> <p>(43) 国際公開日 2000年2月24日 (24.02.00)</p>
<p>(21) 国際出願番号 PCT/JP99/04224</p> <p>(22) 国際出願日 1999年8月5日 (05.08.99)</p> <p>(30) 優先権データ 特願平10/244356 1998年8月17日 (17.08.98) JP 特願平11/56754 1999年3月4日 (04.03.99) JP</p> <p>(71) 出願人 (米国を除くすべての指定国について) 株式会社 荏原製作所 (EBARA CORPORATION) [JP/JP] 〒144-8510 東京都大田区羽田旭町11番1号 Tokyo, (JP)</p> <p>(72) 発明者; および (75) 発明者/出願人 (米国についてのみ) 森 洋一 (MORI, Yoichi) [JP/JP] 〒253-0045 神奈川県茅ヶ崎市十間坂1-6-18-B202 Kanagawa, (JP)</p> <p>(74) 代理人 弁理士 社本一夫, 外 (SHAMOTO, Ichio et al.) 〒100-0004 東京都千代田区大手町二丁目2番1号 新大手町ビル206区 ユアサハラ法律特許事務所 Tokyo, (JP)</p>		<p>(81) 指定国 JP, KR, US, 欧州特許 (DE, FR, GB)</p> <p>添付公開書類 国際調査報告書</p>

(54) Title: METHOD AND APPARATUS FOR TREATING WASTE GAS CONTAINING FLUORO-CHEMICAL

(54) 発明の名称 フッ素含有化合物を含む排ガスの処理方法及び装置



(57) Abstract

A method and apparatus for decomposing a fluorochemical, e.g.,  $C_2F_6$ , by bringing a waste gas (1) containing the fluorochemical into contact with an aluminum oxide (3), e.g.,  $\gamma$ -alumina, heated at, e.g., 800 to 900 °C.  $H_2$  may be present therein in an amount sufficient for converting the fluorine atoms of the fluorochemical to HF. The fluorochemical can be decomposed to a high degree. The aluminum oxide has a long life, and CO generation is little.